

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)			Docket Number (Optional) KASA:019A		SERIAL NO.: NEW APPLICATION		
			APPLICANT(s) Tatsutoshi SUZUKI				
			FILING DATE: April 21, 2004			Group Art Unit	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>EEL</i>	US	5,921,855	7/99	Osterheld et al.	451	527	
<i>EEL</i>	US	5,984,769	11/99	Bennett et al.	451	527	
<i>EEL</i>	US	6,241,585	6/01	White	451	41	
<i>EEL</i>	US	6,572,445	6/03	Laursen	451	10	
<i>EEL</i>	US	6,561,891	5/03	Eppert, Jr. et al.	451	530	
<i>EEL</i>	US	6,238,271	5/01	Cesna	451	41	
<i>EEL</i>	US	5,398,458	3/95	Henriksen et al.	125	13:01	
<i>EEL</i>	US	6,641,471	11/03	Pinheiro et al.	451	526	
<i>EEL</i>	US	6,602,436	8/03	Mandigo et al.	216	88	
FOREIGN PATENT DOCUMENTS							
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
<i>EEL</i>	JP	11-70463	3/99	JAPAN (English Abst.)			X
<i>EEL</i>	JP	47-16044	6/72	JAPAN (Concise Explanation)			X
<i>EEL</i>	JP	63-22002	6/88	JAPAN (Concise Explanation)			X
<i>EEL</i>	JP	2000-94303	4/00	JAPAN (English Abst.)			X
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>EEL</i>				The Science of CMP; August 20, 1997; pages 113-119; Chapter 4, Part III "Structure and Feature of the polishing pad".			
EXAMINER <i>EEL</i>				DATE CONSIDERED	<i>4/12/08</i>		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 509; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.